

Characteristics of high responsivity 8.5 μm InGaAs/InP QWIPs grown by metalorganic vapour phase epitaxy

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Outline

- **Introduction**
- Device structure and characterisation
- Results
- Discussion
- Summary

QWIP Material Systems (8 –14 μm)

- Lattice-matched systems
 - AlGaAs/GaAs/AlGaAs on GaAs substrates
 - InP/ $\text{In}_{0.53}\text{Ga}_{0.47}\text{As}$ /InP ; $\text{In}_{0.52}\text{Al}_{0.48}\text{As}$ / $\text{In}_{0.53}\text{Ga}_{0.47}\text{As}$ / $\text{In}_{0.52}\text{Al}_{0.48}\text{As}$;
 - InP/ $\text{In}_{1-x}\text{Ga}_x\text{As}_y\text{P}_{1-y}$ /InP ($x = 0.47$ y) on InP substrates

- Motivation for this work
 - Larger responsivity of InGaAs/InP QWIPs compared to the mature QWIP system of GaAs/AlGaAs¹
 - Most structures of InGaAs/InP grown by MBE (1-2)
 - Few reports⁽³⁻⁵⁾ by MOVPE

¹Gunapala et.al., APL,**58**(18),2024,1991

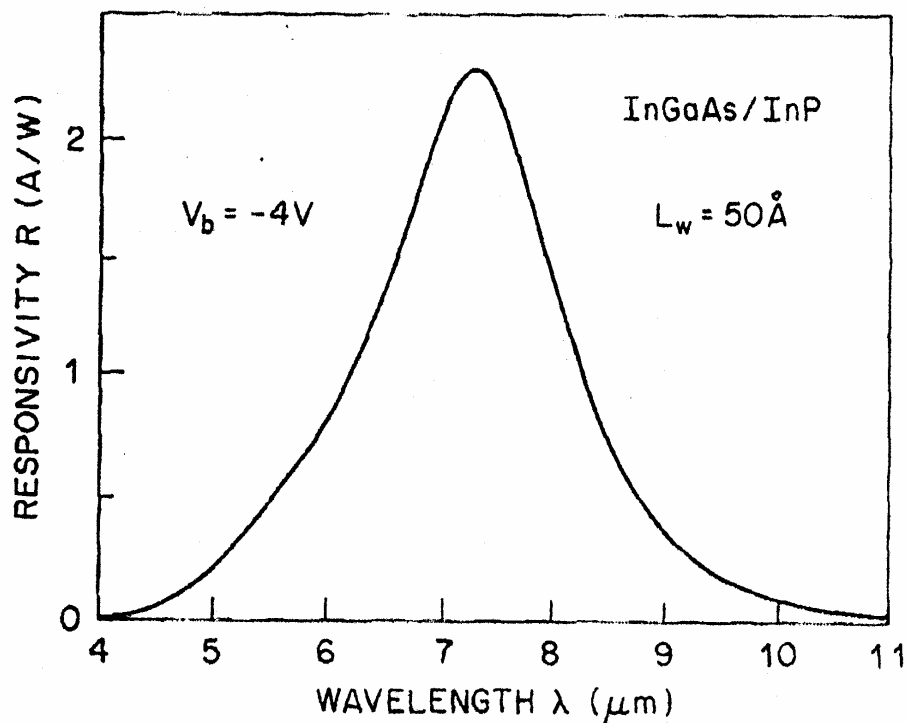
²Jelen et.al., IEEE J. Q.E.,**34**,1124,1998

³Andersson et.al., SPIE **1762**,216,1992

⁴Pham et.al., IEEE E. D. L.,**14**,74,1993

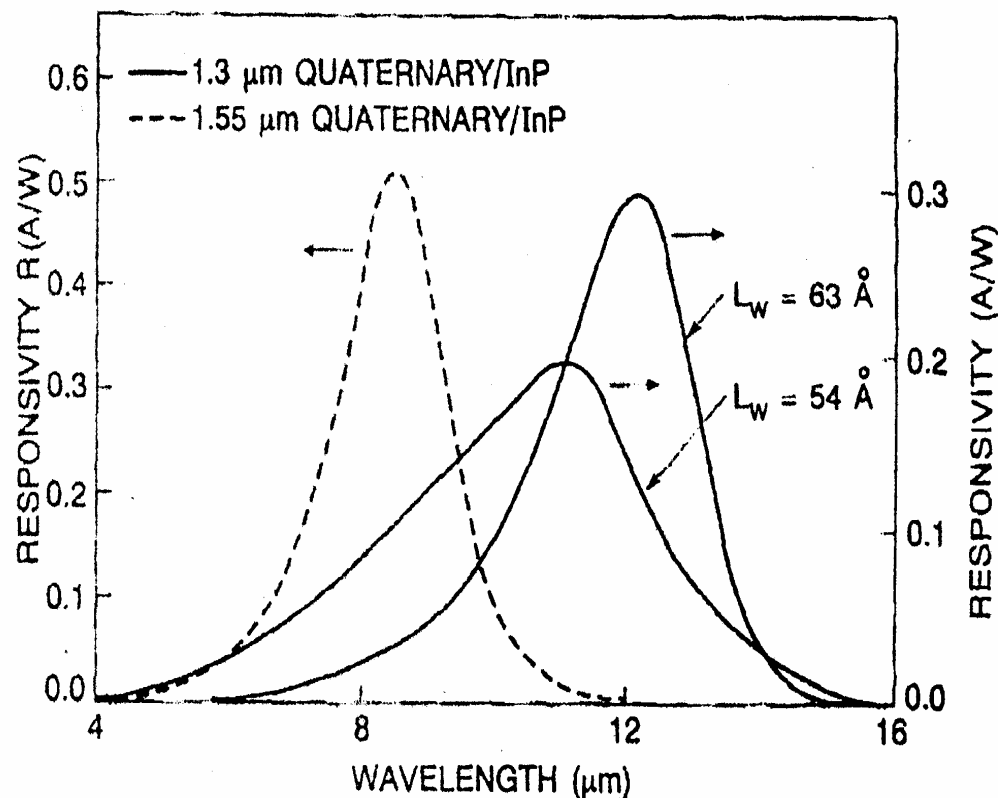
⁵Erdtmann et.al., SPIE **3948**,220,2000

In_{0.53}Ga_{0.47}As/InP QWIPs



- QWs: In_{0.53}Ga_{0.47}As
 - Barriers: InP
 - Lattice-matched to InP
 - InP barriers for higher gain
 - Less alloy scattering in binary material than ternary AlGaAs
 - Higher saturation velocity of InP
 - In_{0.53}Ga_{0.47}As/InP QWIPs have
 - 5 x larger responsivity and
 - 10 x larger gain
- than similar GaAs/AlGaAs QWIPs
- $\Delta E_C = 242$ meV is fixed
 - $\lambda_p \sim 7\text{-}8$ μm by varying L_w

$\text{In}_x\text{Ga}_{1-x}\text{As}_y\text{P}_{1-y}/\text{InP}$ QWIPs



- QWs: InGaAsP
- Barriers: InP
- Lattice matched to InP for $x = 0.47$ y
- InGaAsP QWs for tuning peak detection wavelength
- InP barriers for higher gain
- InGaAsP/InP QWIPs have
 - 2.5 x larger responsivity than similar GaAs/AlGaAs QWIPs
 - 2 x smaller responsivity than $\text{In}_{0.53}\text{Ga}_{0.47}\text{As}/\text{InP}$ QWIPs due to more alloy scattering in quaternary QWs

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QWIP Structure Parameters

Ref.	Growth method	Well / Barrier	Well doping (cm ⁻³)
This work	MOVPE	30 x (68 Å InGaAs/340 Å InP)	5 x 10¹⁷
Gunapala et. al.	MBE	20 x (60 Å InGaAs/500 Å InP)	5 x 10 ¹⁷
Andersson et. al.	MOVPE	50 x (47 Å InGaAs/550 Å InP)	5 x 10 ¹⁷
Pham et. al.	MOVPE	50 x (50 Å InGaAsP/50 Å InP) + 500 Å InP blocking barrier	N/A
Erdtmann et. al.	MOVPE	20 x (60 Å InGaAs/500 Å InP)	1.7 x 10 ¹⁷ 5 x 10 ¹⁷ 1.7 x 10 ¹⁸

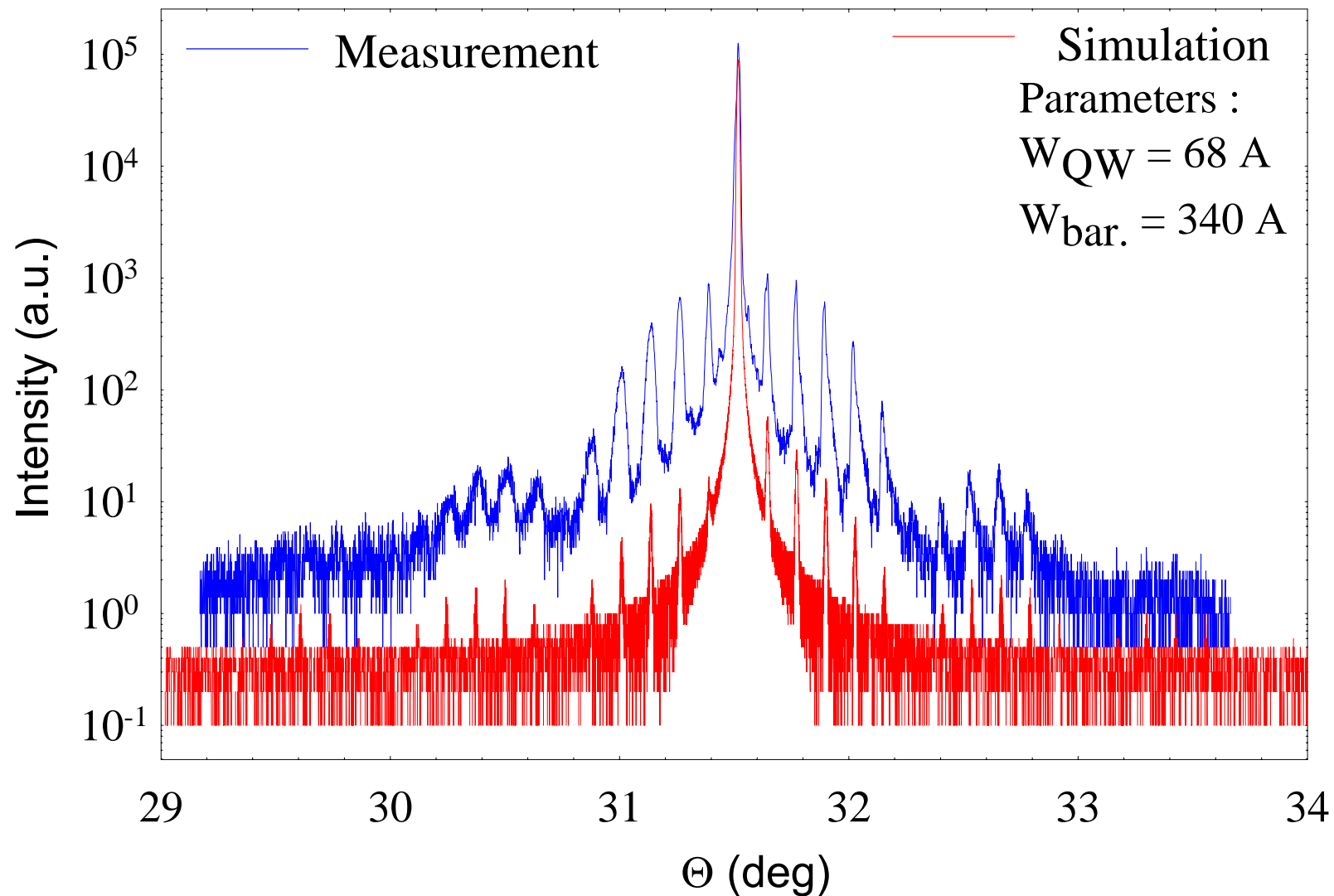
Schematic structure of $\text{In}_{0.53}\text{Ga}_{0.47}\text{As}/\text{InP}$ QWIP ⁸ grown by MOVPE

5000 Å	$n \sim 10^{18} \text{ cm}^{-3}$	n-InP	
340 Å	undoped	InP	
68 Å	$n \sim 5 \times 10^{17} \text{ cm}^{-3}$	n-InGaAs	x 30
340 Å	undoped	InP	
1.0 μm	$n \sim 10^{18} \text{ cm}^{-3}$	n-InP	
400 μm	SI-InP substrate		

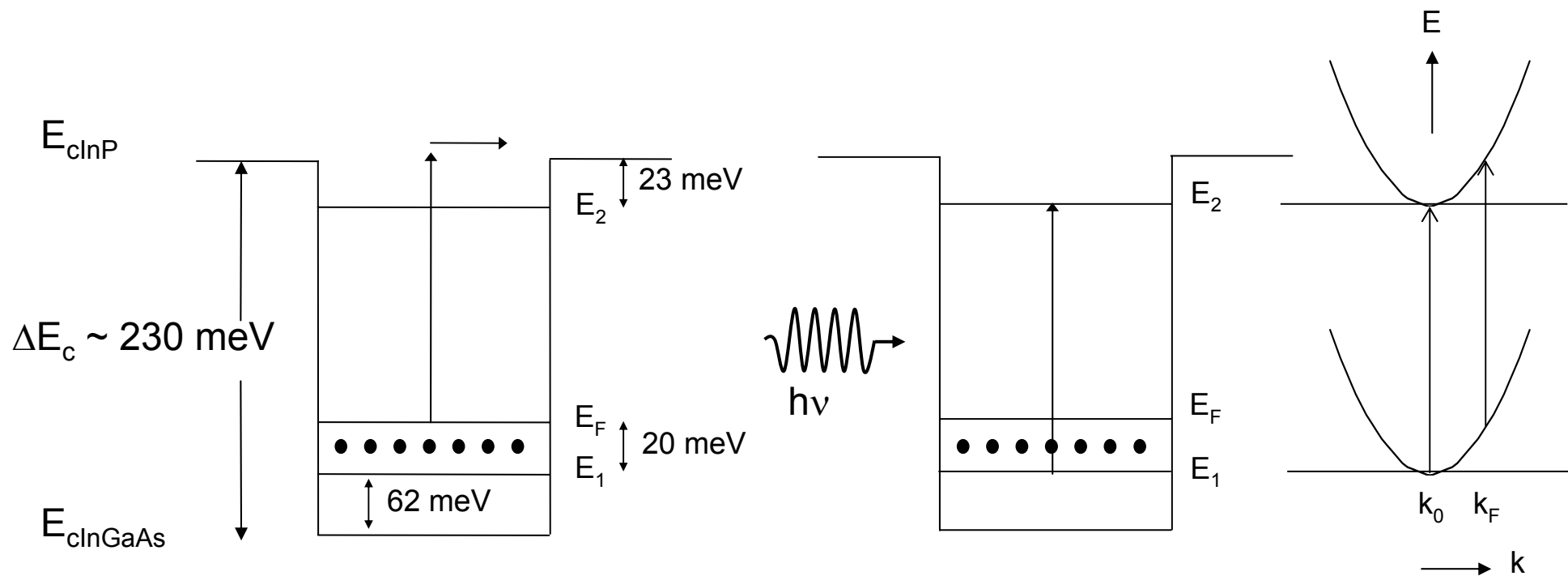
$T_G \sim 625^\circ\text{C}$

Design wavelength $\sim 8.5 \mu\text{m}$

High resolution x-ray diffraction of InGaAs/InP QWIP

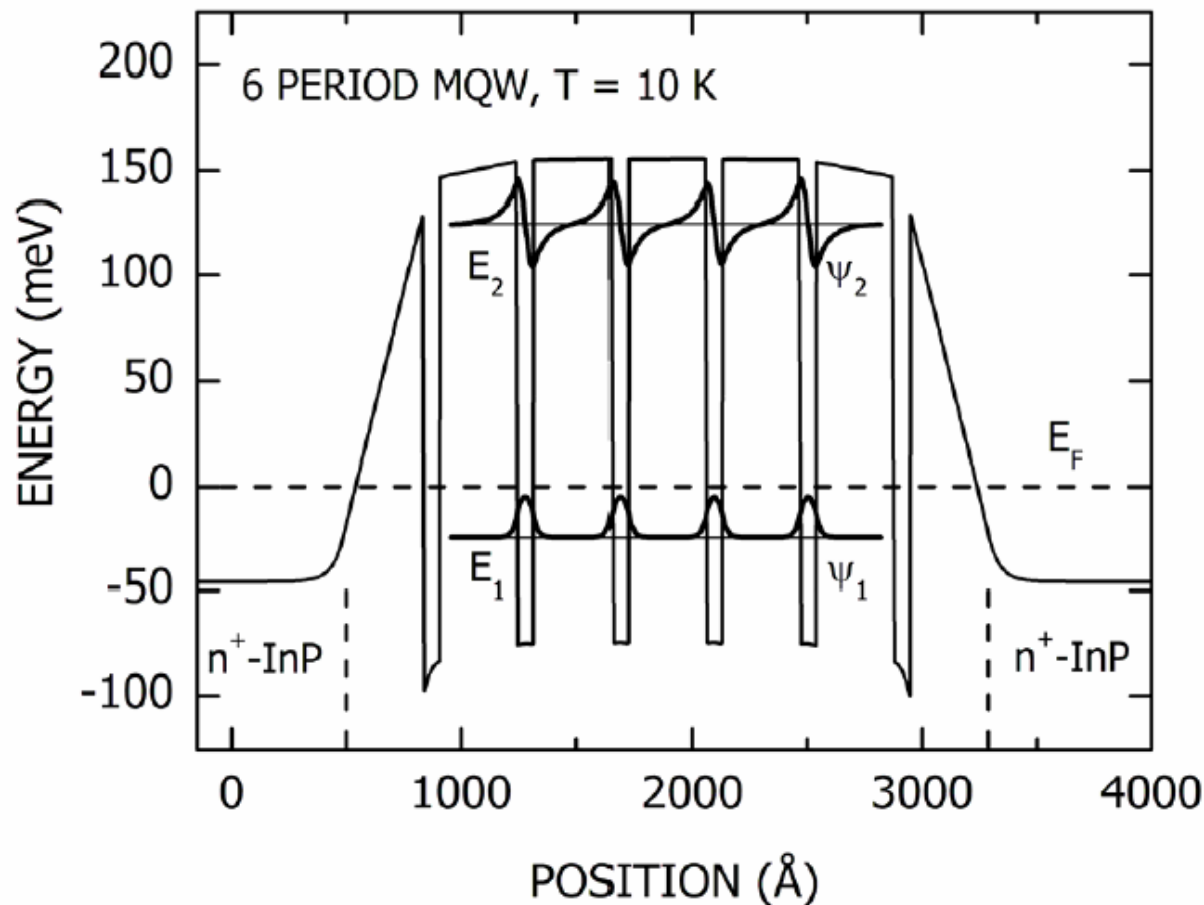


Energy Level diagram of InGaAs/InP QWIP



$$E_{21} \sim 145 \text{ meV}$$

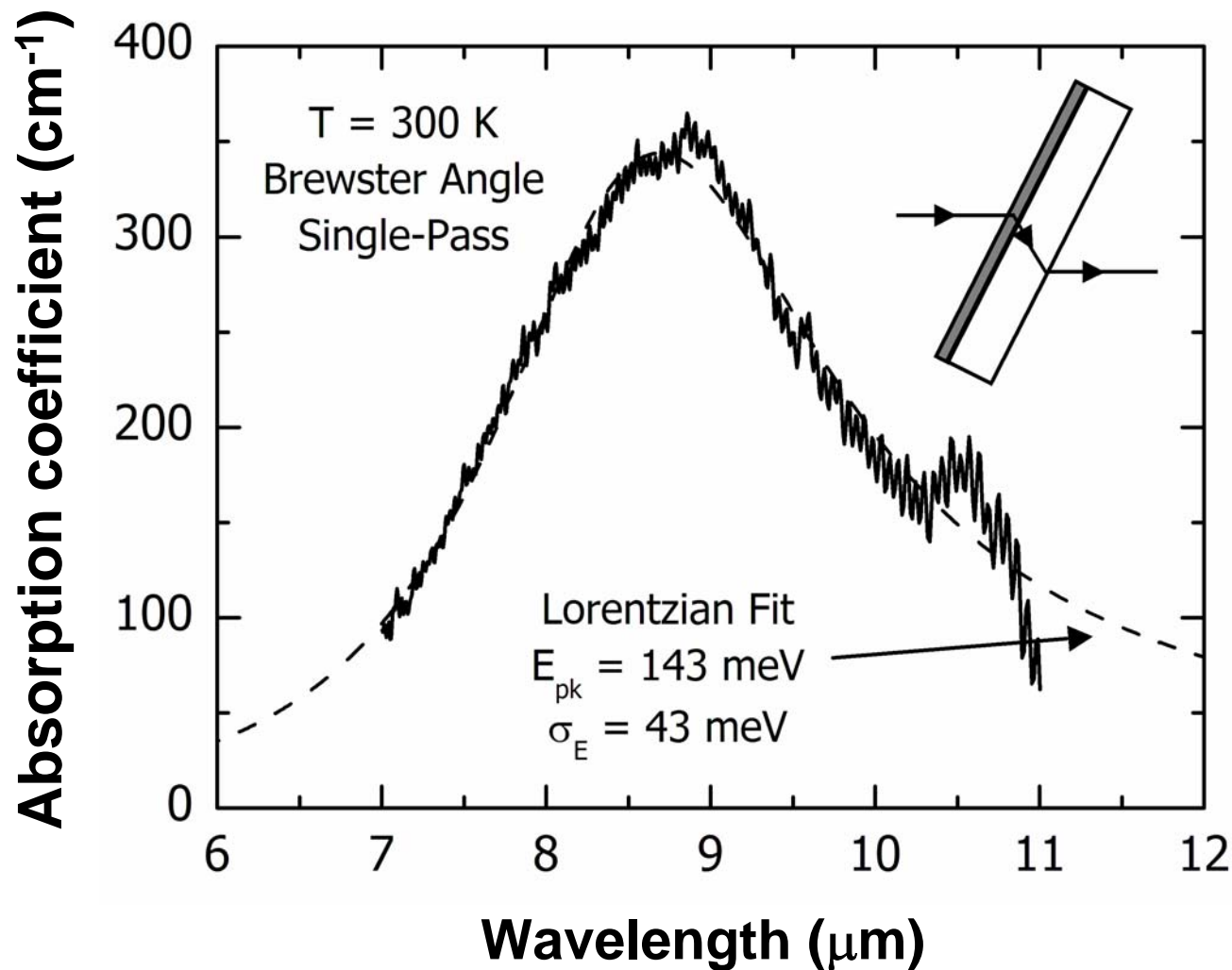
Transfer Matrix Method Calculation



$E_{21} \sim 145 \text{ meV}$; Plasma Energy $\hbar\omega_p = 29.7 \text{ meV}$

$$E_{pk} = \sqrt{E_{21}^2 + \hbar\omega_p^2} = 148 \text{ meV} \rightarrow \lambda_{pk} = 8.4 \mu\text{m}$$

Inter-subband absorption measurement with FTIR



$$\lambda_{pk} \sim 8.7 \mu\text{m}$$

$$\sigma_E/E_{pk} \sim 30 \%$$

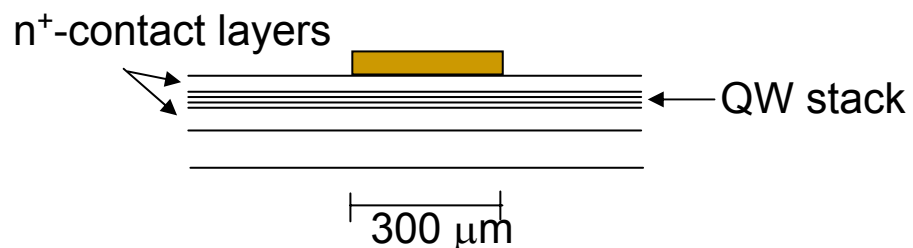
$$\alpha_{pk} \sim 365 \text{ cm}^{-1}$$

$$L \sim 1.258 \mu\text{m}$$

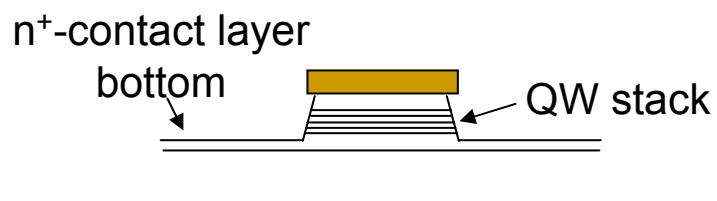
$$\eta_{77\text{K}} \sim 5.6 \%$$

Device Fabrication Process

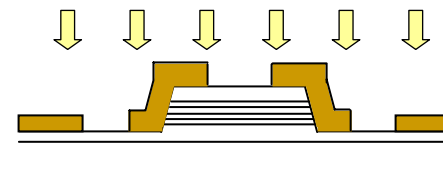
1. Resist mask for mesa etching



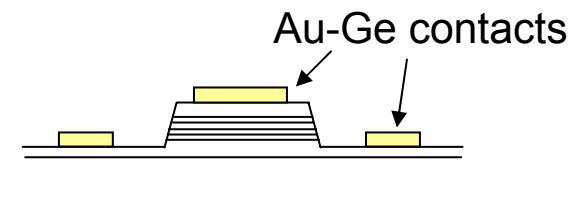
2. Wet chemical mesa etching



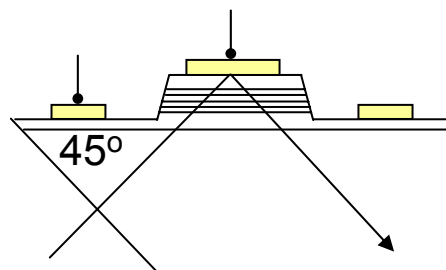
3. Photolithography & metalization



4. Lift-off & annealing



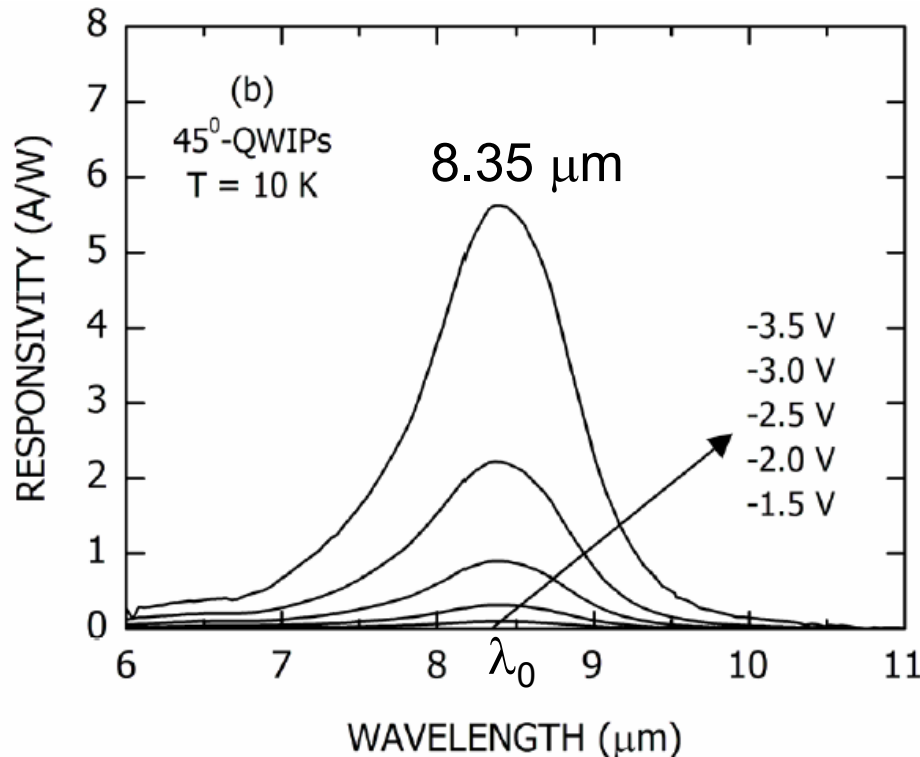
5. Final device after polishing at 45°



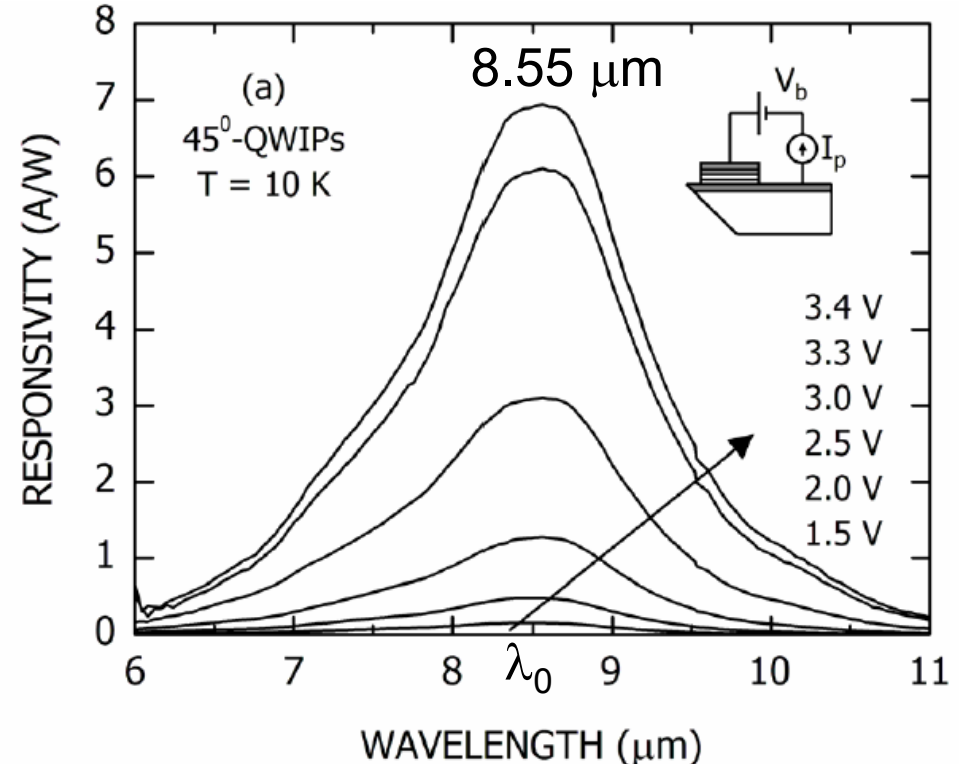
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QWIP Response



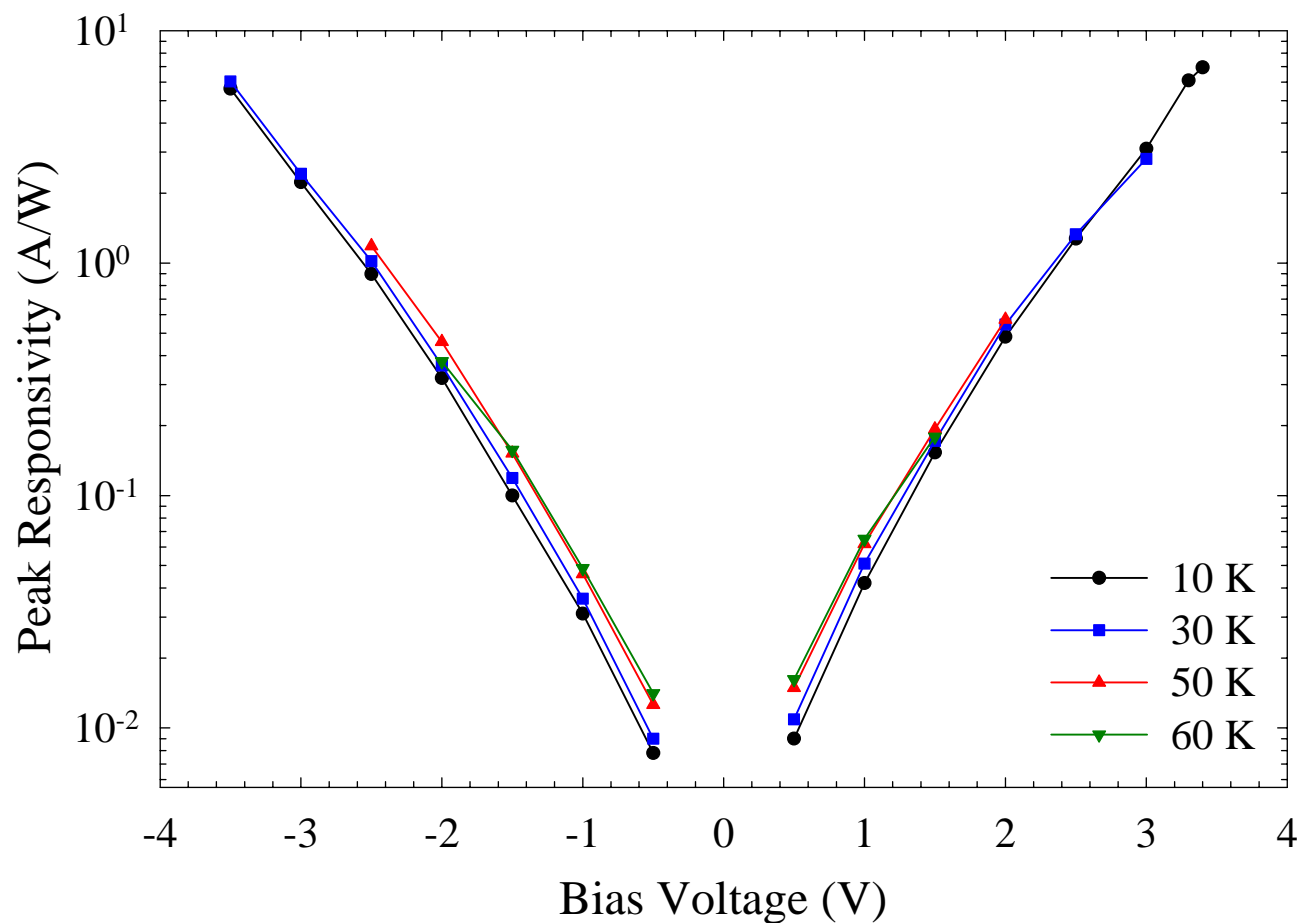
- Tail on short wavelength side
- $\Delta\lambda/\lambda_{pk} \sim 18\%$ +ve bias
~ 13% -ve bias
- $\lambda_0 \sim 8.25 \mu\text{m}$



- $\lambda_c \sim 9.3 \mu\text{m}$ +ve bias
~ 8.9 μm -ve bias
- $R_{pk} \sim 6.9 \text{ A/W}$ +ve bias
~ 5.6 A/W -ve bias

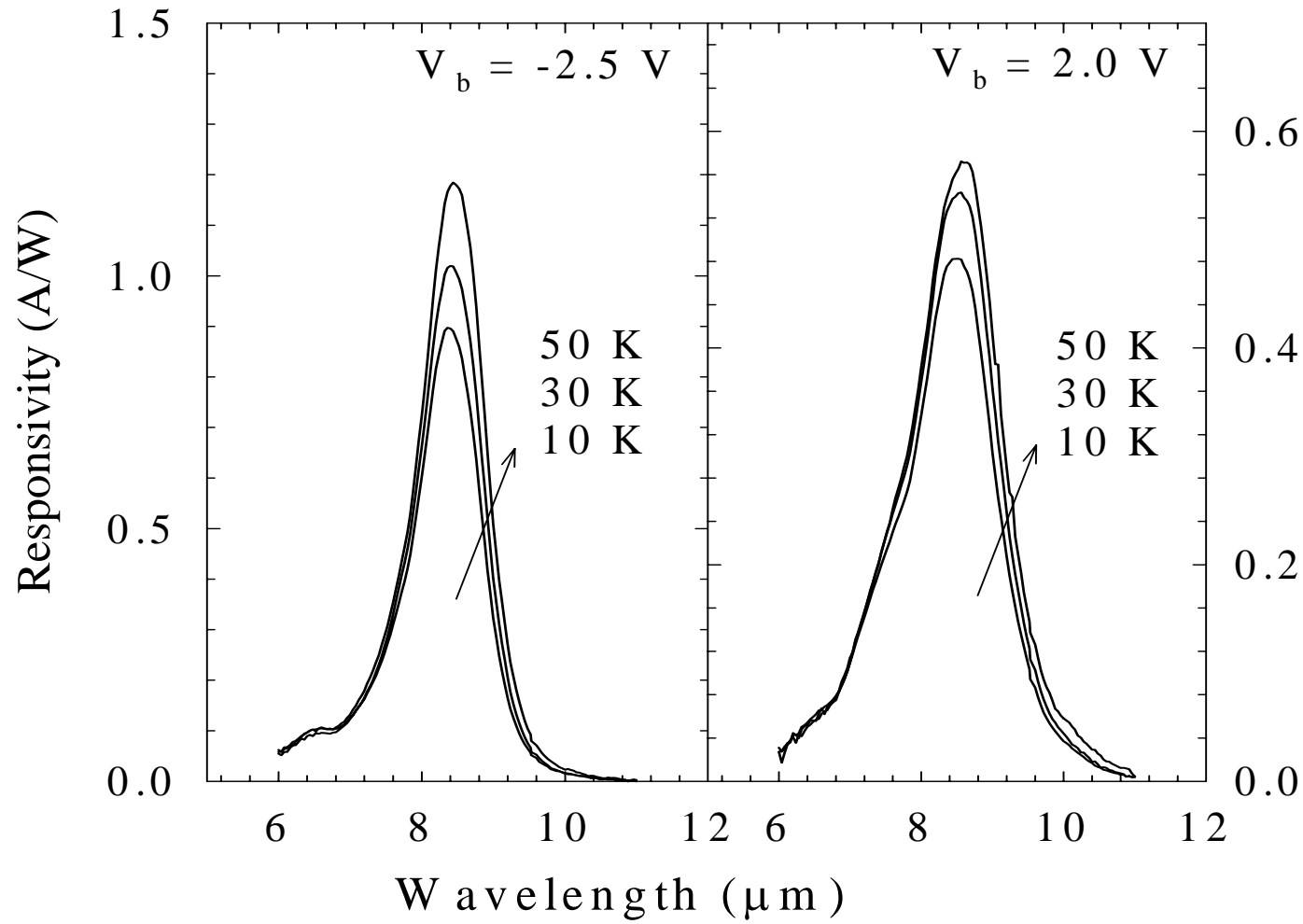
Bias dependence of peak responsivity

Temp: 10 - 60 K



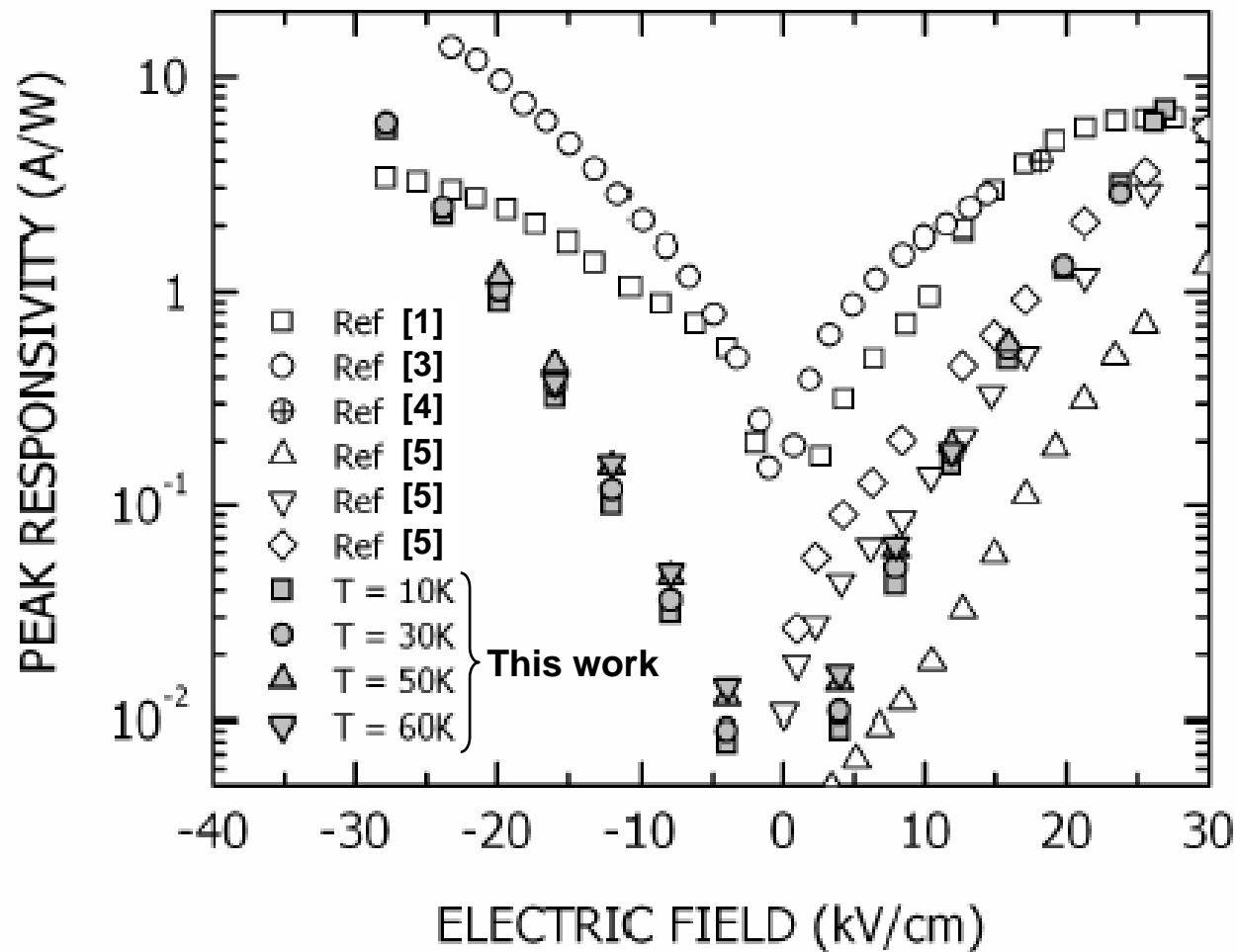
R_{pk} increases nearly exponentially with bias

Temperature dependence of responsivity at fixed bias



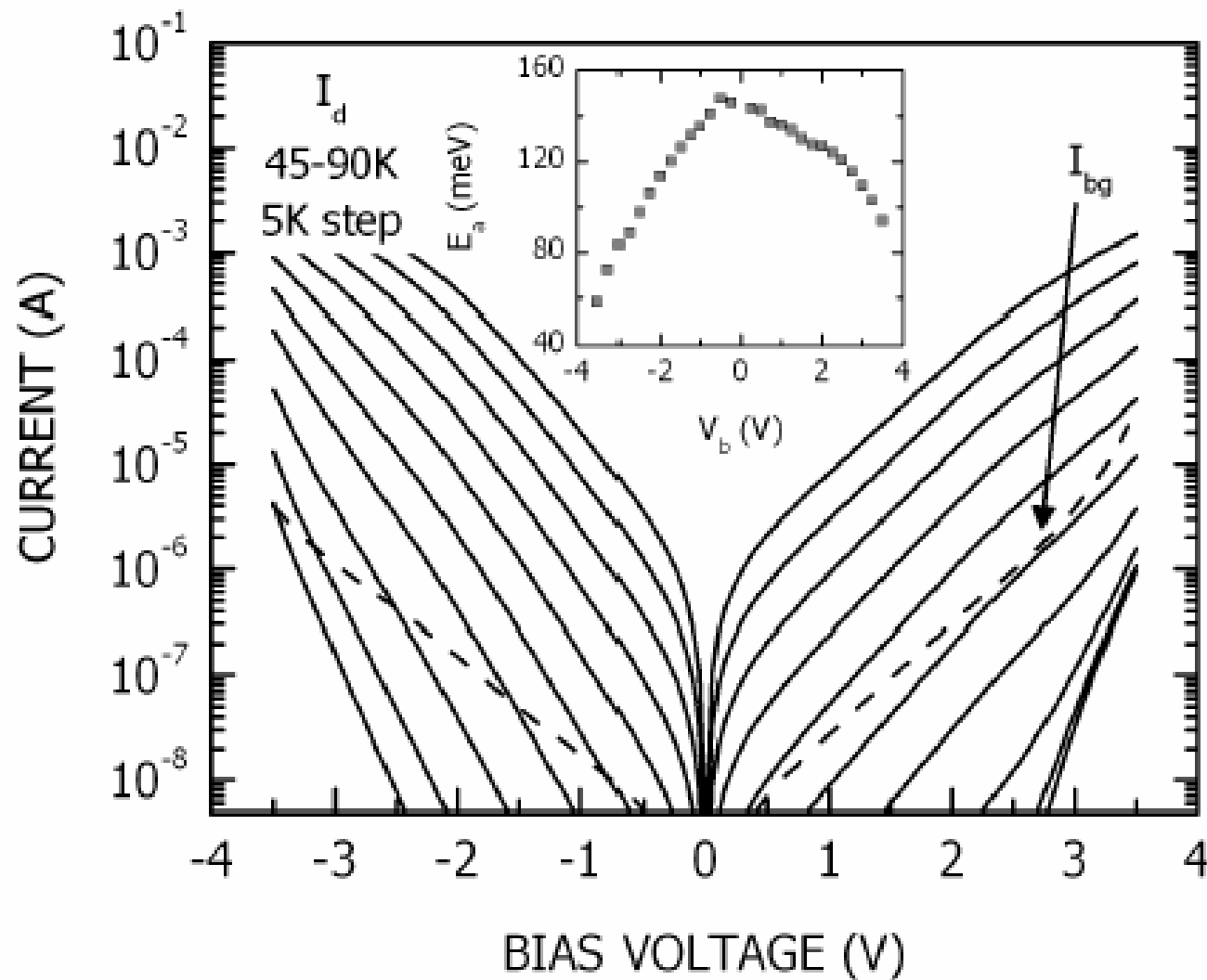
R_{pk} increases with temperature

Comparison of Responsivities with Published Work

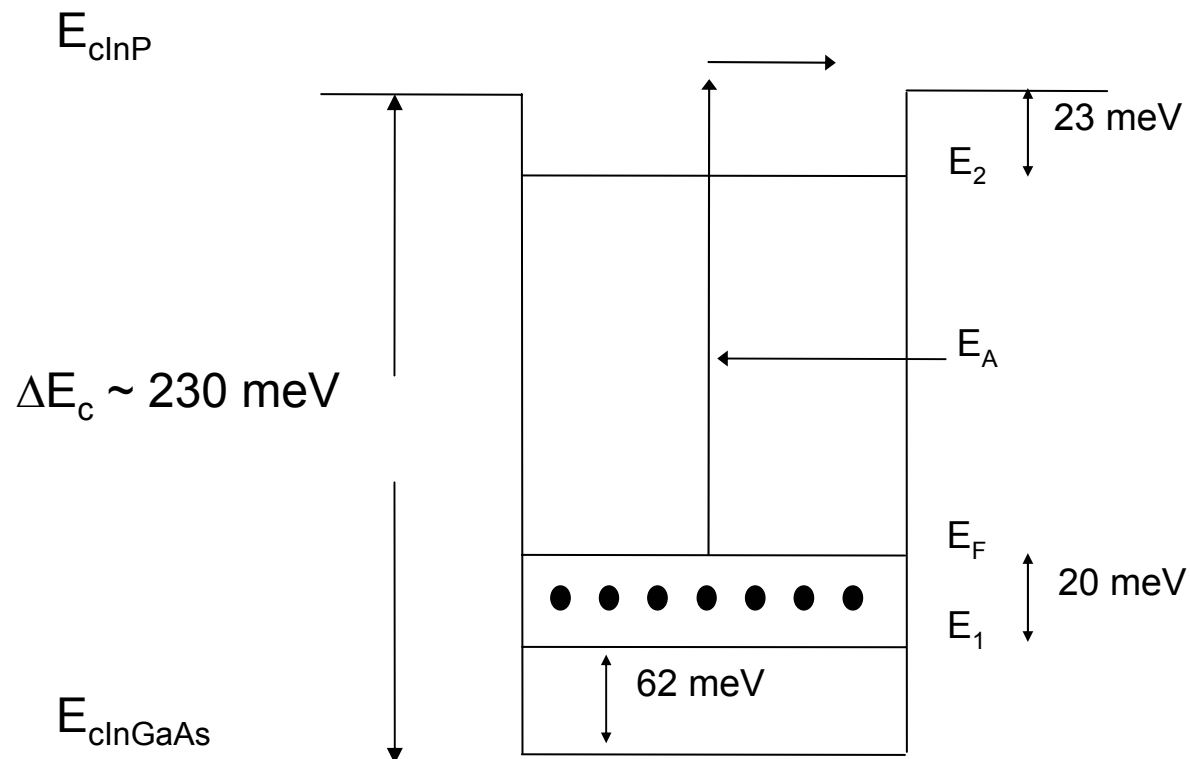


- ¹Gunapala et.al.
³Andersson et.al.
⁴Pham et.al.
⁵Erdtmann et.al.

Dark I – V Characteristics



Activation energy of InGaAs/InP QWIP



Dark current activation energy

$$E_A = \Delta E_c - (E_1 + E_F) \sim 148 \text{ meV}$$

Gain

- Noise gain
(noise measurement)

$$i_n = \sqrt{4eg_n i_d}$$

$$g_n = 21.2 \text{ at } 3.4 \text{ V}$$

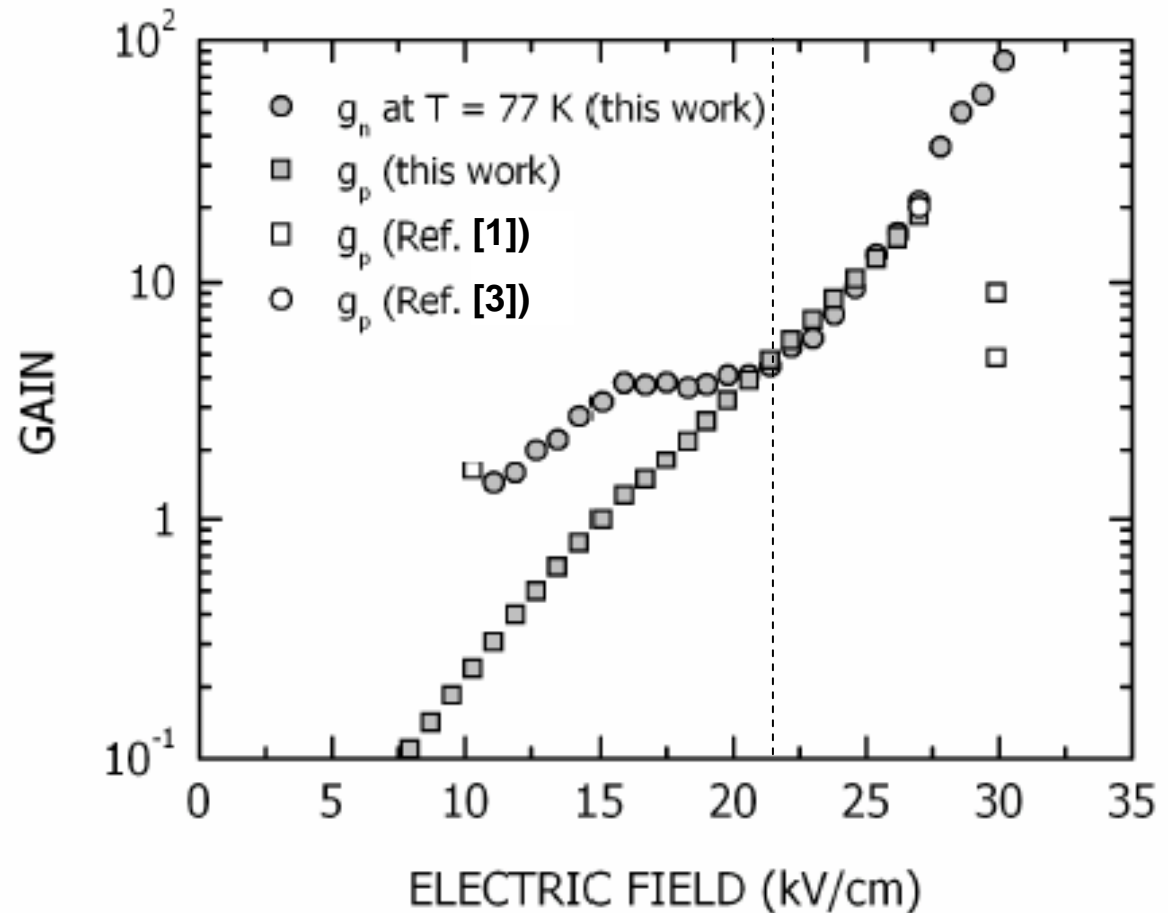
$$= 82 \text{ at } 3.8 \text{ V}$$

Onset of Avalanche
multiplication at
 $E \sim 20 - 25 \text{ kV/cm}$

- Photo Conductive gain
(Responsivity measurement)

$$R_{pk} = \left(\frac{e\lambda_{pk}}{hc} \right) \eta g_p$$

$$g_p = 18.4 \text{ at } 3.4 \text{ V}$$



Detectivity

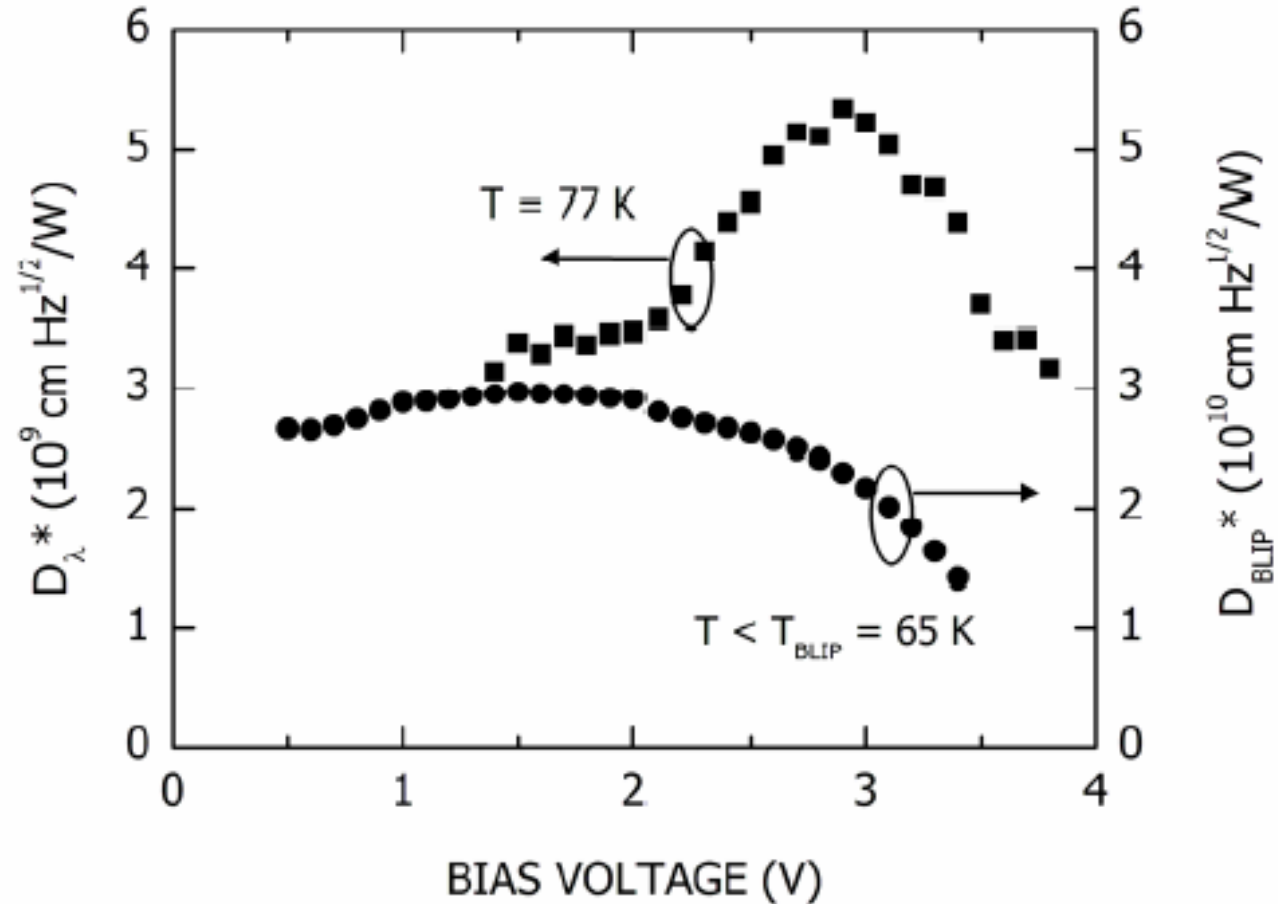
- Peak detectivity

$$D_{\lambda}^* = \frac{R_{pk} \sqrt{A_d \Delta f}}{i_n}$$

- Background limited detectivity

$$D_{BLIP}^* = \frac{R_{pk} \sqrt{A_d \Delta f}}{i_{pn}}$$

$$i_{pn} = \sqrt{4eg_p I_{bg}}$$



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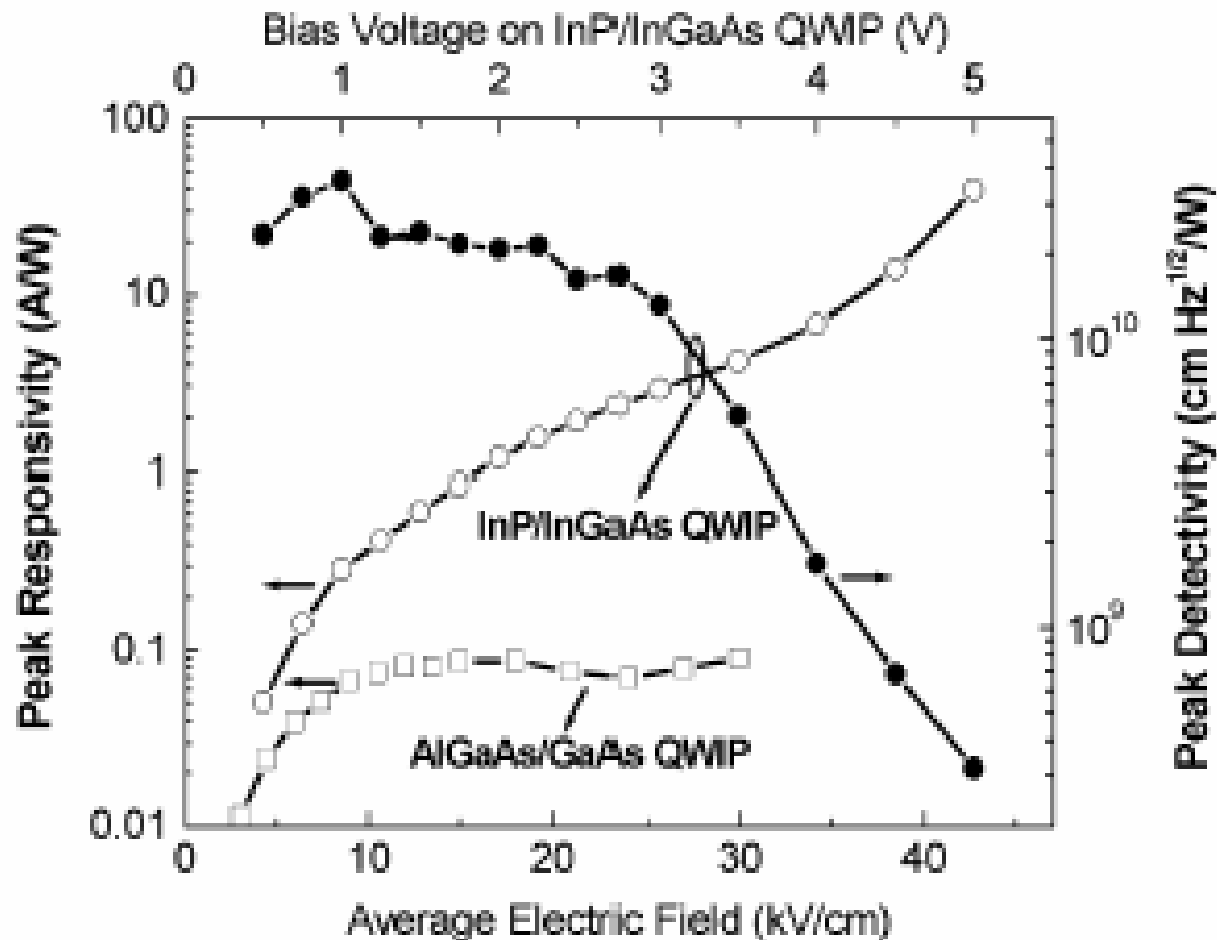
Responsivity

$$R = \frac{e}{h\nu} \eta g = \frac{e}{h\nu} \eta \frac{\tau_c}{\tau_{tr}}$$

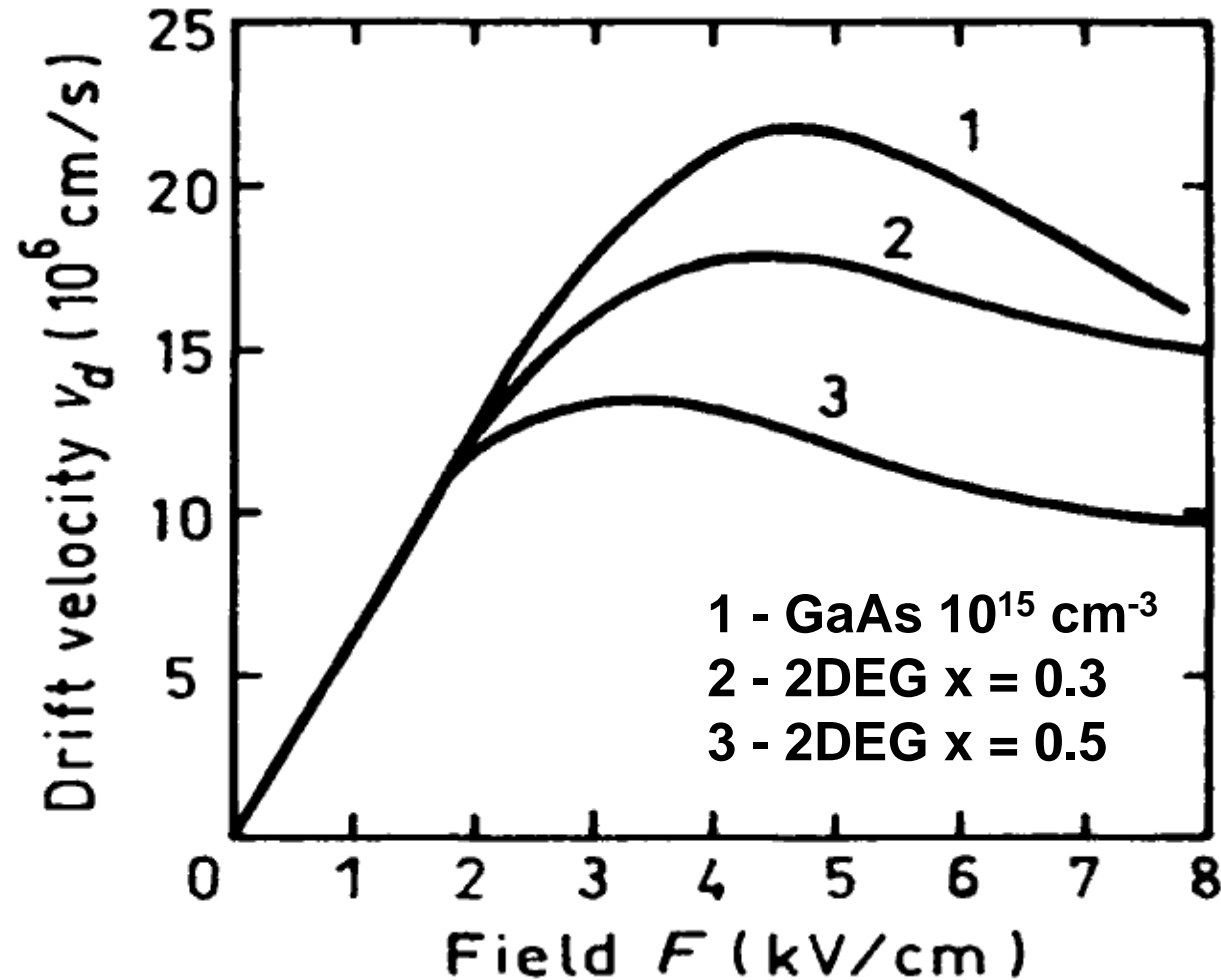
- ❖ Factors controlling τ_{tr}
 - Electron emission from the excited state in QW into barrier
 - High field electron-velocity in the barrier

- ❖ Factors controlling τ_c
 - Distribution of electrons in Γ , L, X valleys
 - Capture of electrons in the QW
electron-phonon interaction

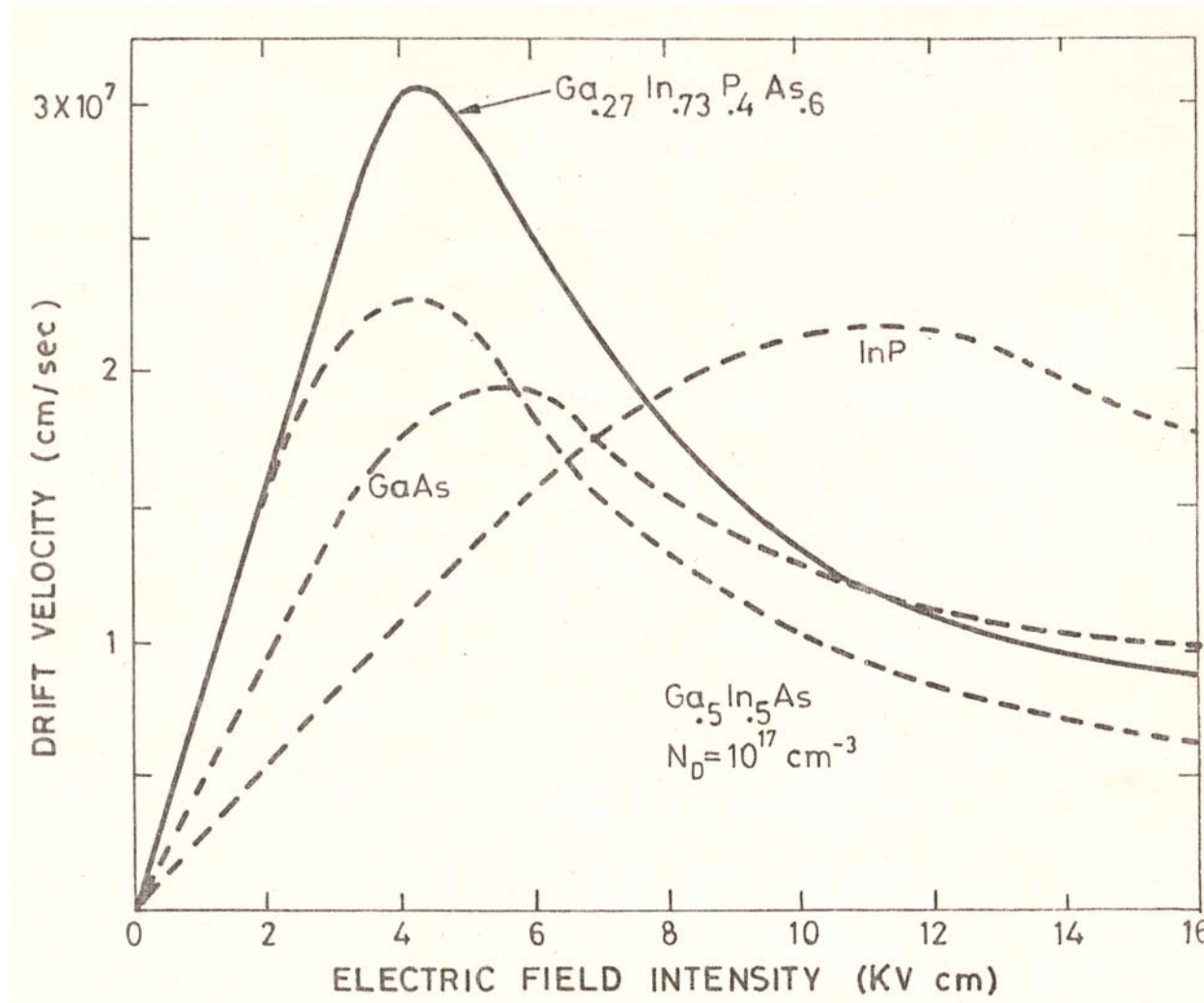
Comparison of peak responsivity and detectivity of GaAs/AlGaAs and InGaAs/InP QWIPs



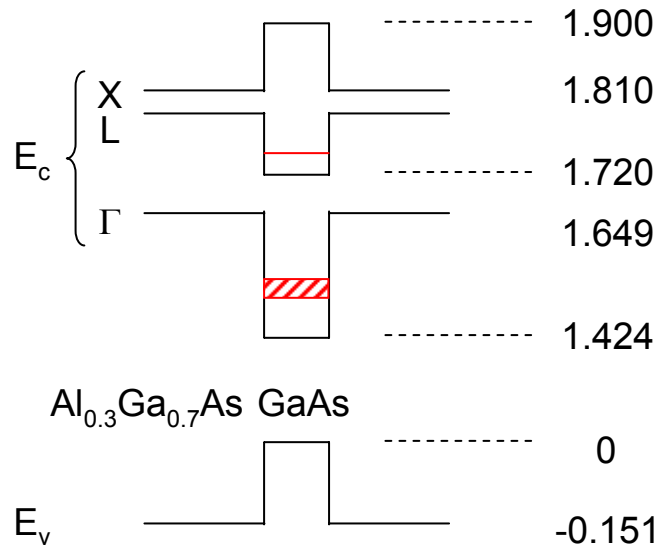
Velocity-field characteristics of GaAs and $\text{Al}_x\text{Ga}_{1-x}\text{As}$



Velocity-field characteristics of InGaAsP, GaAs, InP and InGaAs



GaAs-Al_{0.3}Ga_{0.7}As and In_{0.53}Ga_{0.47}As-InP Band Diagrams



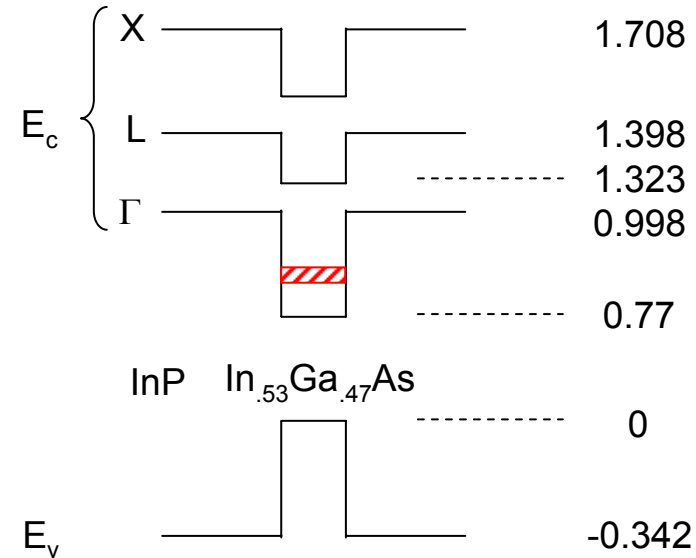
	GaAs	Al _{0.3} Ga _{0.7} As
E_g^Γ	1.424	1.800
E_g^L	1.720	1.928
E_g^X	1.900	1.961

$$\Delta E_g^\Gamma = 0.376 \text{ eV}$$

$$\Delta E_c = 0.225 \text{ eV}$$

$$\Delta E_v = 0.151 \text{ eV}$$

$$\text{Assume } \Delta E_c \sim 0.6 \Delta E_g$$



	In _{0.53} Ga _{0.47} As	InP
E_g^Γ	0.77	1.34
E_g^L	1.323	1.74
E_g^X	1.438	2.05

$$\Delta E_g^\Gamma = 0.57 \text{ eV}$$

$$\Delta E_c = 0.228 \text{ eV}$$

$$\Delta E_v = 0.342 \text{ eV}$$

$$\text{Assume } \Delta E_c \sim 0.4 \Delta E_g$$

Electron Capture in GaAs QW

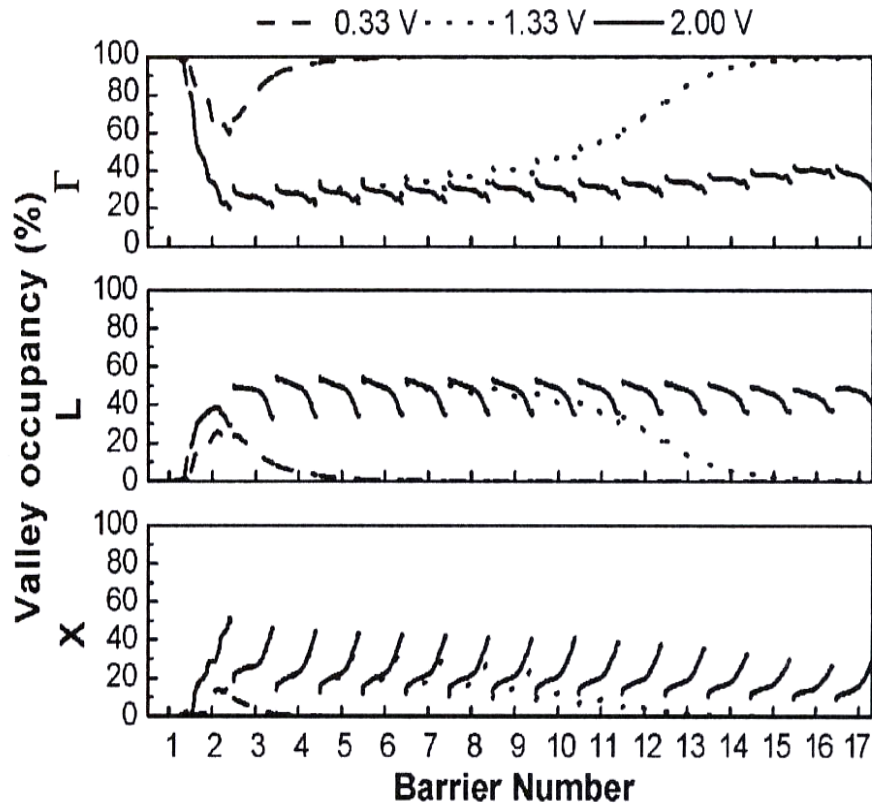


Figure 5. Valley occupancies in the barriers under various bias voltages.

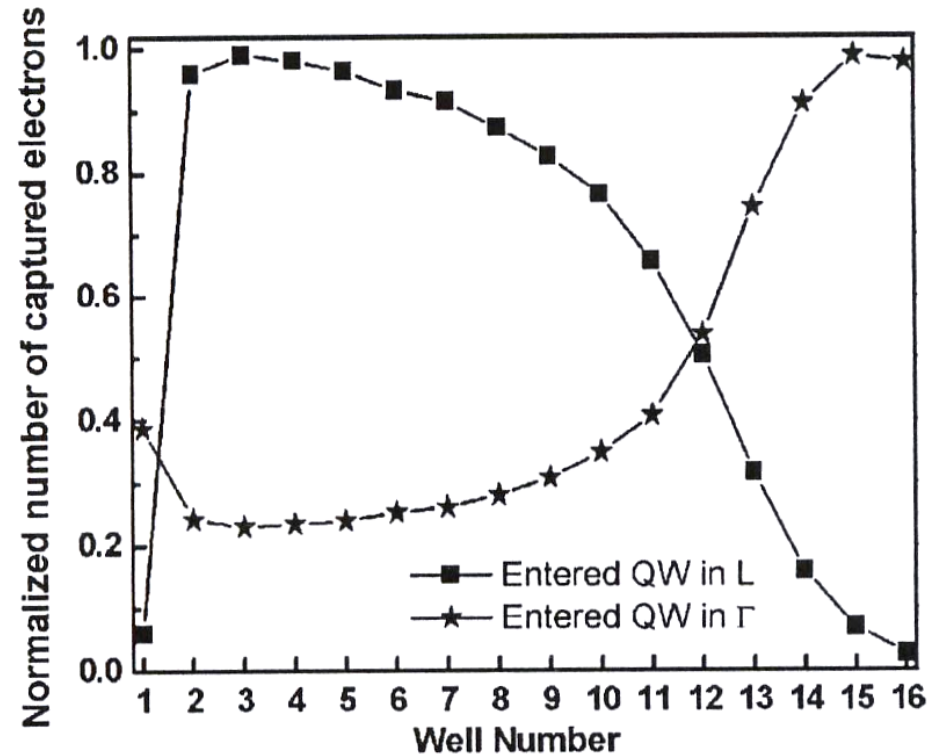
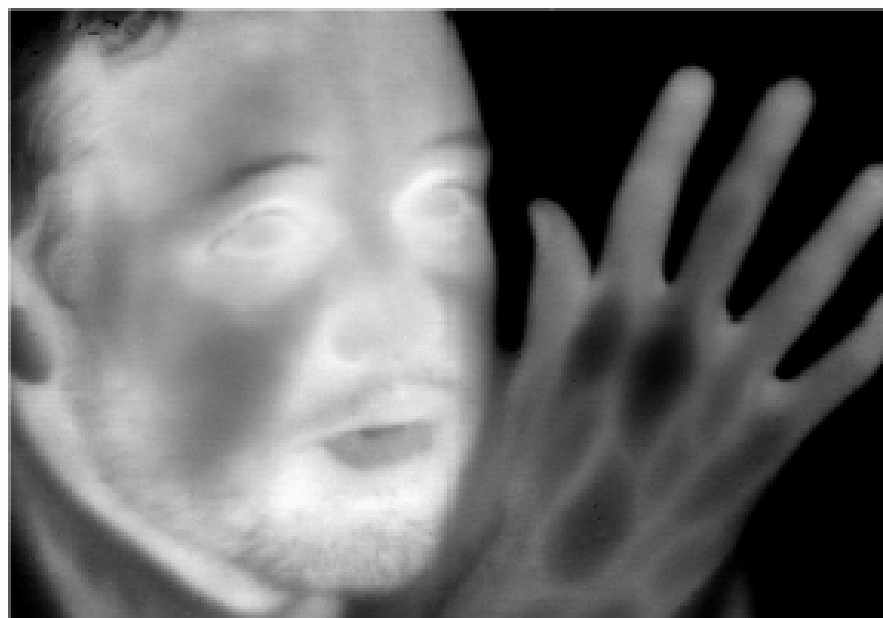


Figure 8. Normalized number of electrons that enter the GaAs QW region in Γ and L valleys and are captured into the same QW of the Γ valley under 1.33 V bias.

Some Questions

- i. What is the origin of asymmetry of dark I – V and photo I – V characteristics ?
- ii. Dark current is larger for – ve polarity, while the photo current is larger for + ve plarity. What causes this ?
- iii. What is the relation of structural non-uniformities particularly of (i) the compositional & (ii) doping concentration, to the measured characteristics ?
- iv. What are the performance limiting aspects of InGaAs / InP QWIPs Vis - a - Vis GaAs / AlGaAs QWIPs ?

Thermal Images from InGaAs/InP QWIP FPA



Indoor Image



Outdoor Image

- Sensor Temperature ~ 70 K

Cellek et.al., IEEE J. Q. E., Vol. 41, No. 7, 980 – 985, July 2005

Summary

- $\text{In}_{0.53}\text{Ga}_{0.47}\text{As}/\text{InP}$ B-B QWIPs grown by MOVPE have performance comparable to the devices fabricated from materials synthesized by MBE.
- In order to be able to use the InGaAs / InP QWIP devices for imaging purposes, it is necessary to identify the material aspects such as non-uniformities, interfaces, which limit the uniformity and performance over the arrays, particularly their dark current and noise characteristics.